

Supplies Provided by NUFAB

Gowning

All required gowning supplies

Personal Protective Equipment (PPE)

All required PPE

Chemicals

Photoresists: SU8-3050, SU8 3025, SU8-3010, SU8 TF 6002, S1813, S1805, LOR 1A, LOR 5A, AZ 5214E-IR, AZ P4620, AZ nLOF2035

Developers: MF319, AZ 400K (1:4 and concentrated), SU8 Developer, AZ 917MIF, AZ 300MIF

Ebeam Resists: PMMA 950 A2, PMMA 950 A5, ZEP520A, ma-N 2403

Ebeam Developers: MIBK, ZED-N60, DisChargeH₂Ox2 (anti-charging agent)

Resist Removers: Remover 1165, Nanostrip

Adhesion Promoters: HMDS, SurPass 4000

Solvents: Acetone, 2-Propanol

Etchants: Chrome Etchant, Buffered Oxide Etch 6:1 and 10:1, Aluminum Etchant, Nanostrip, HF, Fe₂O₃ Etchant, Copper Etchant, Gold Etchant TFA, KOH, TMAH 25%, H₂O₂, NH₄OH, HCl, Citric acid, H₂SO₄, HNO₃, H₃PO₄,

General Cleanroom Supplies

Silicon Wafers (various sizes)

Wafer and Mask Holders (various sizes)

Cleanroom Notebooks

Cleanroom Paper

Cleanroom Wipes (two types)

Storage Boxes

Petri Dishes

Aluminum Foil

Equipment Specific Supplies

AJA Sputter Targets: Cu, Al, Cr, Mo, Ti, Ni, Fe, W, Si, SiO₂, Si₃N₄, ITO, Ag, Au, Pt, Nb, Ta

AJA E-beam Evaporator: Crucibles for all materials

ALD Precursors: Triethylaluminum, Diethylzinc, Tris(dimethylamino)silane, Tetrakis(dimethylamido)hafnium(IV), Tetrakis(dimethylamido)titanium, Tetrakis(dimethylamido)zirconium(IV), Tris(diethylamido)(tert-butylimido)tantalum(V), Molybdenum hexacarbonyl, Tetrakis(2,2,6,6-tetramethyl-3,5-heptanedionato)cerium(IV), Tetrakis(dimethylamino)tin(IV), Water, Ozone, Oxygen, Oxygen plasma, Hydrogen, Hydrogen plasma, Ammonia, and Ammonia plasma

ALD Cook: Trimethylaluminum, Tetrakis(dimethylamido) titanium, Tetrakis(dimethylamido) hafnium, Tetrakis(dimethylamido) zirconium

Denton Thermal Evaporator: Boats for all materials, chrome-coated tungsten rods

Evaporation Materials: Mo, W, Ag, Al, Cu, Ni, Ti, Cr, Au

Mask and Maskless Aligners: Blank Photomasks (for mask making) 4"x4" (Cr), 5"x5" (Cr), 4"x4" (Fe₂O₃), 5"x5" (Fe₂O₃)

Contact Angle Measurement: Disposable pipet tips.

Filmetrics: Si wafer for background measurement

Electrical Test Probe Station: Spare contact probes.

Electronic Printer: Silver ink

Parylene coater: Parylene C pellets

Gases

Silane, Ammonia, Hydrogen, Dichlorosilane, Forming Gas (4%H₂, Balance N₂), UHP nitrogen, Oxygen, N₂O, CF₄, C₄F₈, C₃F₆, C₃F₈, CHF₃, Helium, SF₆, Argon, Liquid CO₂